IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of	MAIL STOP RCE
Shigeyuki Akimoto et al.	Group Art Unit: 2624
Application No.: 10/556,916) Examiner: Vanchy Jr., Michael J.
Filed: November 15, 2005) Confirmation No.: 1621
For: OUTER SURFACE-INSPECTING METHOD, MASTER PATTERNS USED THEREFOR, AND OUTER SURFACE-INSPECTING APPARATUS EQUIPPED WITH SUCH A MASTER PATTERN))))

AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated July 24, 2008, please amend the above-identified patent application as follows: